

# Modules & Testing (MAT) PBDR Overview

#### Brad Benson (L2 scientist) for WBS 1.06 Plenary Session, Thursday, March 11, 2021



# Outline

- Modules & Testing (MAT) Scope
- Requirements
  - Detector, Readout, Modules (DRM) FY21 R&D Plan
  - Production Testing
  - SAT, LAT Interfaces
- Design Discussion and Parallels
  - Module design
  - Horn Arrays and Interface Wafers
  - Detector module testing

Module Assembly & Testing: Parallel → 14:00 Convener: Bradford Benson (Fermilab; University of Chicago) Modules Notes Module Design and Assembly 12:30 Speakers: Adam Anderson (Fermilab;), Greg Derylo (Fermilab) **Testing and Testbeds** 13:00 Speaker: Dr Bradford Benson (Fermilab; University of Chicago) Interfaces Wafers and Horn Arrays 13:30 Speaker: Sara Simon (Fermilab) Slides

Thursday 1230-1400 (Pacific)

12:30

## Module and Testing Scope

#### 1. Module structure and assembly

Design module structure that Ο holds together DRM components, interfacing with SAT & LAT groups

#### **Optical coupling** 2.

Design and build feedhorns and 0 interfaces wafers that form mm-wave integrating cavity for detector.

#### Integrated module Testing 3.

- Perform set of optical and dark Ο tests to validate integrated performance of detector module
- Characterize and verify wafer 0 performance on pace matching wafer fab through Production.



CMB-S4 Collaboration Meeting, March 8-12, 2021

WBS 1.04

1.05

WBS 1.03

WBS

1.05

#### **Requirements Overview**

#### High-level driving requirements include:

Requirement	Trace	Driver	Verification
Measure: Detector Dark Properties	MR 1.1, 1.2, 2.0, 3.0, 4.0	Verify detector wafer. Electro-thermal properties (e.g., saturation power, loop gain) of the TES need to be within an acceptable range to meet required instrument sensitivity.	Dark measurements of every detector wafer in an assembled detector module at 100 mK operating temperature.
Measure: Detector Module Optical Coupling	MR 1.1, 1.2, 2.0, 3.0, 4.0	Verify detector module optical coupling. Efficiency and frequency response of mm-wave coupling to TES needs to be within an acceptable range to meet required instrument sensitivity.	Mm-wave/optical measurements of every detector wafer in an assembled detector module at 100 mK operating temperature.
Measure: Integrated Module Sensitivity	MR 1.1, 1.2, 2.0, 3.0, 4.0	Verify detector module sensitivity. Sensitivity (efficiency, noise, yield, etc.) of integrated module (with readout) needs to be within an acceptable range to meet required instrument sensitivity.	Dark and optical measurements of every detector module with readout at 100 mK operating temperature.
Rate: Assembly and Testing	Schedule	Detector fabrication feedback. Detector module assembly and testing needs to provide measurements at a rate sufficient for detector fabrication development during all phases of project.	

## MAT Requirement: R&D / Proto Testing

DETECTOR WAFERS SLAC Detector Microfab. Facility Specification LBNL/SeeOC Detector Wafer Fabrication Marvell Detector Wafer Fabrication ANL Detector Wafer Fabrication JPL Detector Wafer Study

> 100mK READOUT **Chips and SOUID Housing Fabrication** Readout Housing and Circuit Board Fab. Integrate 100mK Readout Units Test 100mK Readout Units

> > 4K and 300K READOUT **Component Design and Fabrication** Assemble and Qualify Readout Units

> > > MODULE ASSEMBLY

**Design Module Components** Procure Module Components **Procure Interface Wafers and Feedhorns Teststand Cryostat Design Qualify Cryostat Teststand Facility** Assemble Modules Module Dark Testing Module Optical Testing





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01 4K SQUID amplifie

1.04.05 Warm electronics

Custom fabrication

02 Readout Module

Hardware (Qty 757

Internet Cons

See B. Flaugher's **Plenary Detector Talk** 



## **MAT Requirement: Production Testing**

- Rates and detector types discussed with each site and iterated.
- Production rates require minimum ramp-up in capabilities at all sites
- Additional capacity is possible at most sites, with appropriate warning
- Plan to reoptimize based on performance, cost and schedule at least annually

PRODUCTION		Split years into part A and B for transition to new detector type									
	FY23A	FY23B	FY24A	FY24B	FY25A	FY25B	FY26A	FY26B	FY27A	FY27B	Total
Site 1 = ANL	2	2	8 8	10	10	10	10	8	10	10	86
Site 2 = JPL	2	2	8 8	8	14	16	16	16	12	6	106
Site 3 = SEEQC	2	2 4	8 10	10	16	16	16	16	4	4	102
Site 4 = NIST	2	2 1	8 8	8	10	12	14	16	16	14	108
Site 5 = SLAC					8	12	16	11	11	10	68
Site 6 = Marvell	1	1 3	3 4	. 5	4	4	4	4	4		33
Total Science Grade	9	3	5 38	41	62	70	76	71	57	44	503
~ Number of wafer modules to test (inc. 12% overage and 67% vield)	15	5 5	9 64	69	104	117	127	119	95	74	841

**MAT Req:** Assemble and test ~600 detector modules over 3-year period

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#### **Key Interfaces: Readout+SAT**







# 1) Module Design







- Proposing a new v2 module design, enabled by higher density wiring on MUX Readout chip
- Helps several interface issues:
  - Readout box fit on back of module
  - Minimizes twisting and length of flex cables

See A. Anderson's MAT Parallel Talk

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### 1) Module Design: SAT Interfaces

#### • See A. Anderson's MAT Parallel Talk

- WIth v2 design, the proposed SAT module layout fits better
- However, it is still tight, and will need to find ~2-mm from somewhere for module to fit.





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# 1) Module Design: FY21 DRM R&D

- FY21 DRM R&D plan calls for detector module testing of prototype detector wafers by Summer 2021
- Full detector and readout module design will not be ready on this schedule
- Designing intermediate detector and readout module that could still test ~700 detectors / wafer, and fit in baselined prototype DR testbeds



#### See A. Anderson's MAT Parallel Talk

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## 2) Horn Arrays and Interface Wafers

- Spline-profiled feedhorns made of (gold-plated) Aluminum 6061
- Silicon coupling "interface wafers" that sandwich detector wafer that form integrating cavity for OMT



See S. Simon"s MAT Parallel Talk

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# 2) Horn Arrays

- Spline profiles optimized for performance requirements→ simulated estimates of systematic effects, efficiency
- Final design requires set inputs:
  - Set pixel size
  - Defined waveguide cutoff and bands
  - Aperture stop angle
  - Any mechanical constraints (e.g. length)
  - Set input requirements
- Will need to decide when inputs are frozen





See S. Simon's MAT Parallel Talk

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## 2) Interface Wafers



Figure 43: Left: A photonic choke wafer. Center: A waveguide interface plate. Right: A backshort array.

- NIST demonstrated process and design over past decade.
- For CMB-S4, need to seek alternative fabrication sites given number of wafers and cost.
- Early stages of writing RFI and discussions with potential vendors, both internal to S4 (SeeQC, SLAC) and commercial vendors

See S. Simon's Parallel Talk

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Readout Parallel Talk

## 3) Detector Module Testing



#### Baseline Plan (from Agency Review):

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 After CD-1, design and build 8x new CMB-S4 specific cryostats capable of testing ~6x detector wafers modules per cooldown, which will be spread over 2-3 testing sites.

**Production** 

**Test Cryostats:** 

Shared design

with LAT-CR or

SAT single

tube?

LAT-CR



## Summary/Conclusions

- Module design:
  - Making progress on prototype module design which is close to meeting requirements
  - FY21 DRM R&D will require intermediate design to match testing schedule
- Horn Arrays and Interface wafers.
  - Horn array production relatively straightforward, though detailed horn design will need inputs from SAT+LAT teams for detailed simulation & optimization.
  - Beginning RFI process for interface wafer production from fabrication sites, production will likely set schedule for early DRM optical testing.

#### • Detector Module Testing

- Started outfitting 3x testbeds for DRM FY21 R&D testing, will expand to optical testing later in FY21 to match interface wafer and funding schedule.
- New testbeds can be brought online with more warm readout electronics (See G. Haller's Readout Parallel talk)
- Production testbeds will be designed after CD-1 to line up with FY25 production testing schedule.







#### **CDFG RFI Summary**

- Based on the detector parameters for LAT mid frequency bands (90/150)
- Two layouts: LAT MF (5.3mm pitch) and SAT-like MF (9.4mm pitch)
- Wafers will be assembled into modules
- Minimum goal: Dark tests
- Optical tests if possible (not in FY2021, maybe in CY21)
- Testing procedure included in RFI
- Changes since original RFI May 2020
  - Dec. 2020 High Tc Psat targets for the LATs were lowered (requires NDF for bare module tests, easier to fabricate)
  - Bondpad layout was changed from NIST (12 clumps of 25 pairs, 70micron pitch) to make it easier for bonding: 100 micron pitch
  - Frequency mapping to pads not specified; not important for CDFG tests, but critical for final layouts





90GHz	Parameter	Low	Target	High	
Science TES	Psat (pW)	2.8	3.5	4.6	
	Tc (mK) (at fixed Psat)	139	139 160		
•	$\frac{T_c^2 P_{sat}}{T_{c,0}^2 P_{sat,0}}$	19 19	1	1.32	
* Rn (mOhms)		8	12	16	
High-Tc TES	Psat (pW)	26	29	(readout limit)	
	Rn	2*Rn_science	2.5*Rn_science		
	Tc	2.5*Tc_science	-		

150 GHz	Parameter	Low (pW)	Target (pW)	High (pW)	
Science TES	Psat (pW)	6.0	7.5	9.9	
	Tc (mK) (at fixed Psat)	139	160	184	
	$\frac{T_c^2 P_{sat}}{T_{c,0}^2 P_{sat,0}}$	-	1	1.32	
• Rn (mOhms)		8	12	16	
High-Tc TES	Psat (pW)	49	54	(readout limit)	
	Rn	2*Rn_science	2.5*Rn_science		
	Тс	2.5*Tc_science	-	2	

Table 1: Deployment detector parameter targets and acceptable ranges.

#### Recent challenges: Interface wafers

Interface/Coupling wafers: need to develop fabrication at multiple vendors (beyond NIST)

- Detector Fab sites interested
- RFI to go out soon
- Responses and available funding will impact schedule for optical tests
- Need to know detector layout to start fabrication

FY2021: Dark tests for CDFG wafers

Goal for CY2021: Optical tests





## **Module / Detector Interface**

- Prototype S4 detector wafer design specification developed by CDFG + detectors WBS + module/test WBS (CMBS4-doc-161-v6)
- LAT (shown on right) and SAT 90/150 GHz designs satisfy pBD requirements
- Alignment with horns achieved with pin-and-slot to handle differential thermal contraction
- TES bondpads around perimeter
- Gold bondpads to improve heat-sinking around perimeter
- Based off SO design and experience





#### **Aluminum Feedhorns**

- Main modification for CMB-S4 is using Aluminum arrays
- **Demonstrations**: BLAST-TNG, APEX-SZ, SPT-SZ all used, aluminum feedhorn arrays coupled to MKIDs or TESes
- **SO**: Baselining AI feedhorn arrays with OMT coupling (bottom)
  - Enables enhanced RF and superconducting magnetic shielding with natural high pass filter from waveguide
  - Easier to assemble, good heat sinking, robust to thermal cycling
  - Mounting features can be machined into feed array
  - Alignment with pin + slot
  - Fabrication status (January-2021):
    - Beginning SO production MF (90/150 GHz) at U. Michigan shop.
      - Piggy-back fabrication of a set of CMB-S4 LAT MF and SAT MF arrays on top of this run.
    - SO prototype of UHF (220/280 GHz) beginning at U. Chicago shop.
    - Continue to explore alternate vendors for (larger-scale) production fab.



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#### **Interface Wafers**

- Interfaces wafers: Includes the photonic choke, waveguide interface plate (WIP), and backshort wafer.
- Working with NIST on CMB-S4 MOA to share design, process steps, and potential procurement of interface wafers. Signed MOA is imminent.
- For FY21 R&D testing, will procure a set of three LAT MF interface wafers directly from NIST for tests this summer.
- FNAL (S. Simon) will work with NIST to explore commercializing interface wafer fabrication. Initial discussions with two vendors.

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Credit: Simon

clamp springs